

AMENDMENTS TO THE SPECIFICATION

Please replace paragraph [1] with the following amended paragraph:

[0001] The application is a divisional of U.S. Patent Application Serial No. 10/209,983, now U. S. Patent No. 6,627,538 B2, filed July 31, 2002, by Applicants, Ilan Gavish and Yuval Greenzweig, entitled "Focused Ion Beam Deposition," which is a continuation of U.S. Patent Application, Serial No. 09/753,108, filed December 30, 2000, now U.S. Patent No. 6,492,261.